

Exhibit B (6 pages)

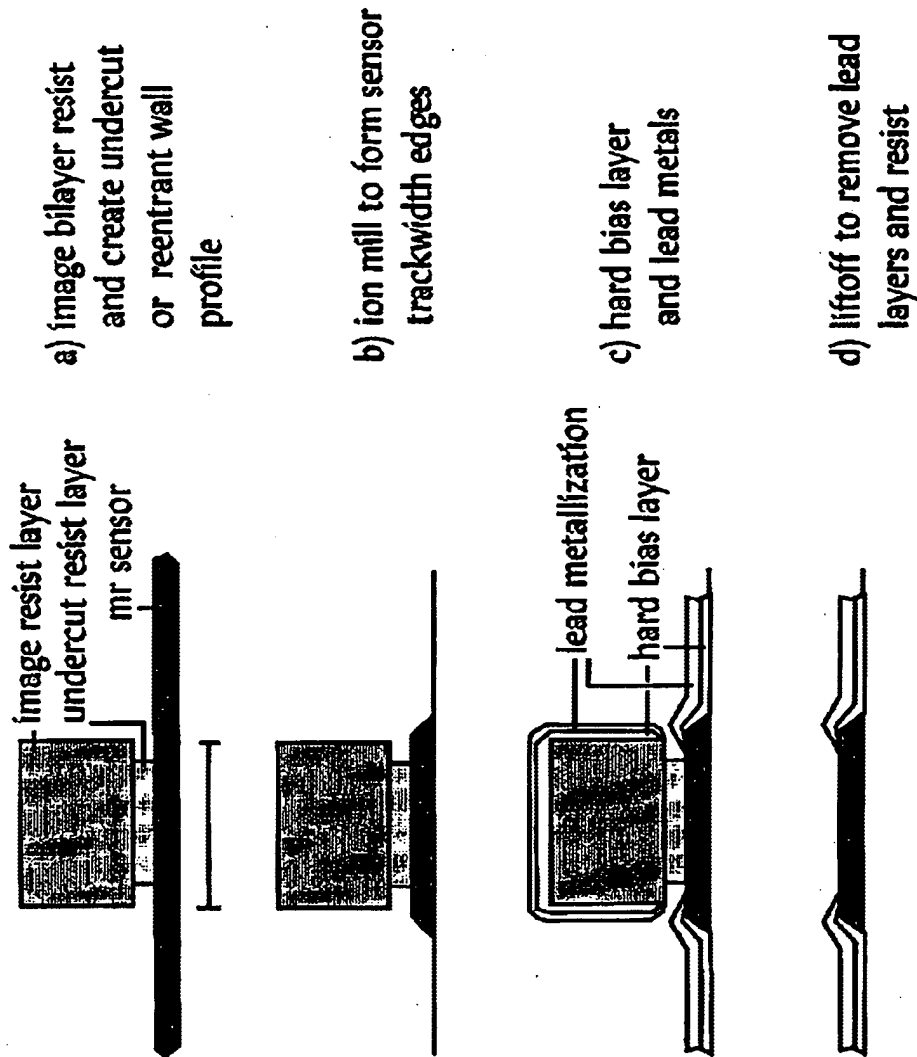


Figure 1. Bi-layer Resist Processing for MR Sensors

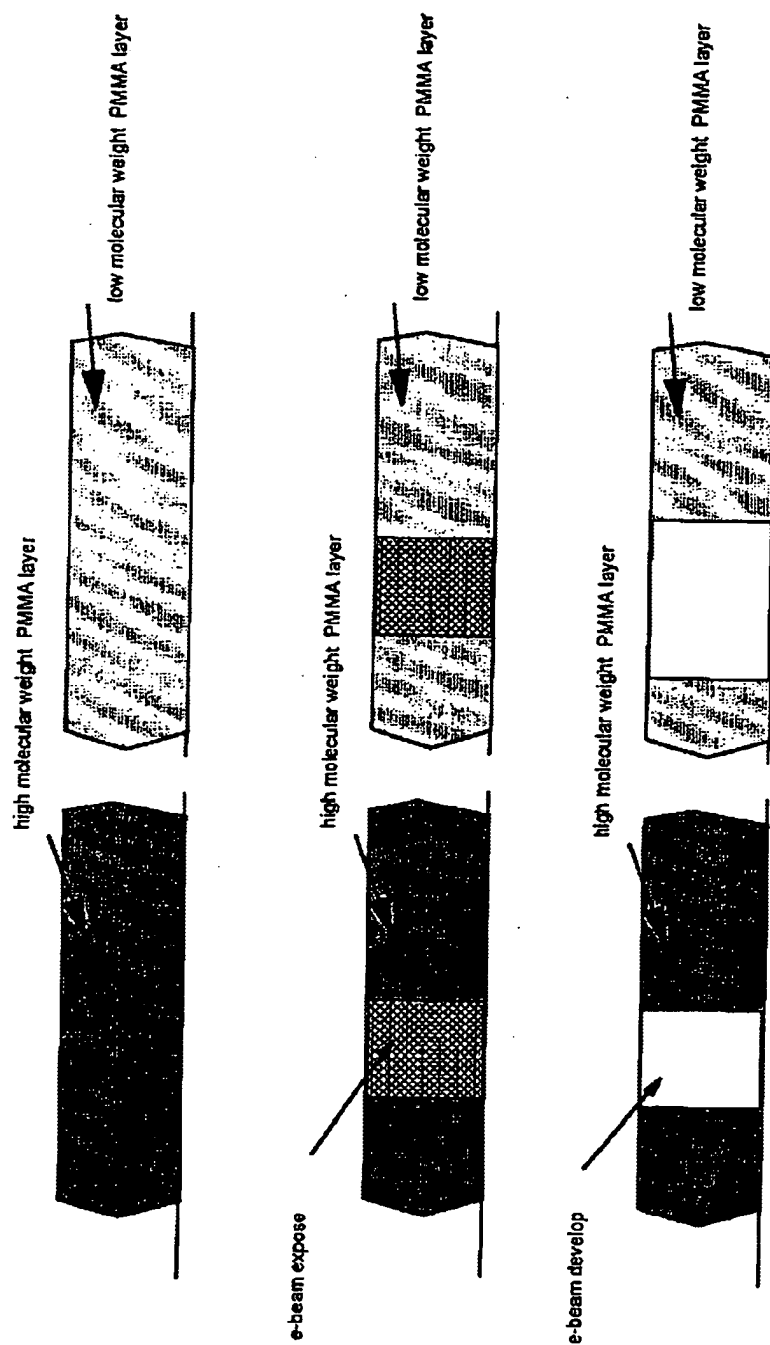


Figure 2. Linewidth Characteristics of Molecular Weight PMMA

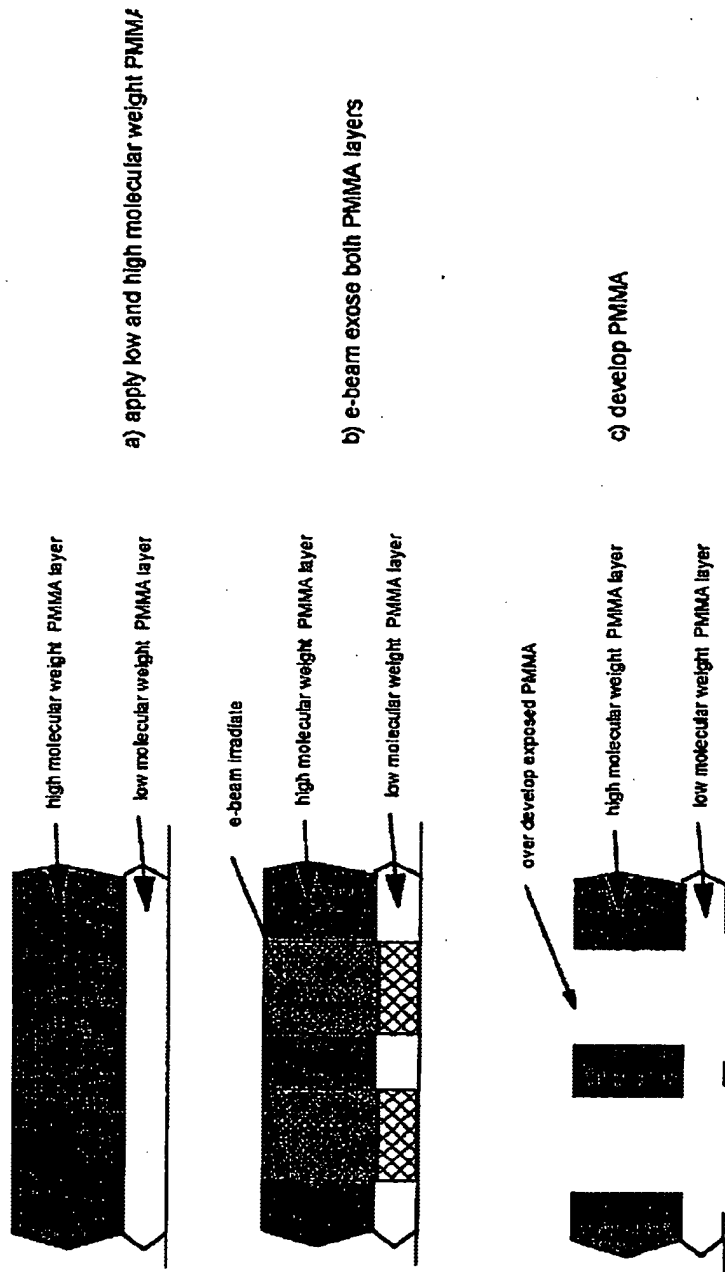


Figure 3. PMMA Bilayer Undercut Resist Structure

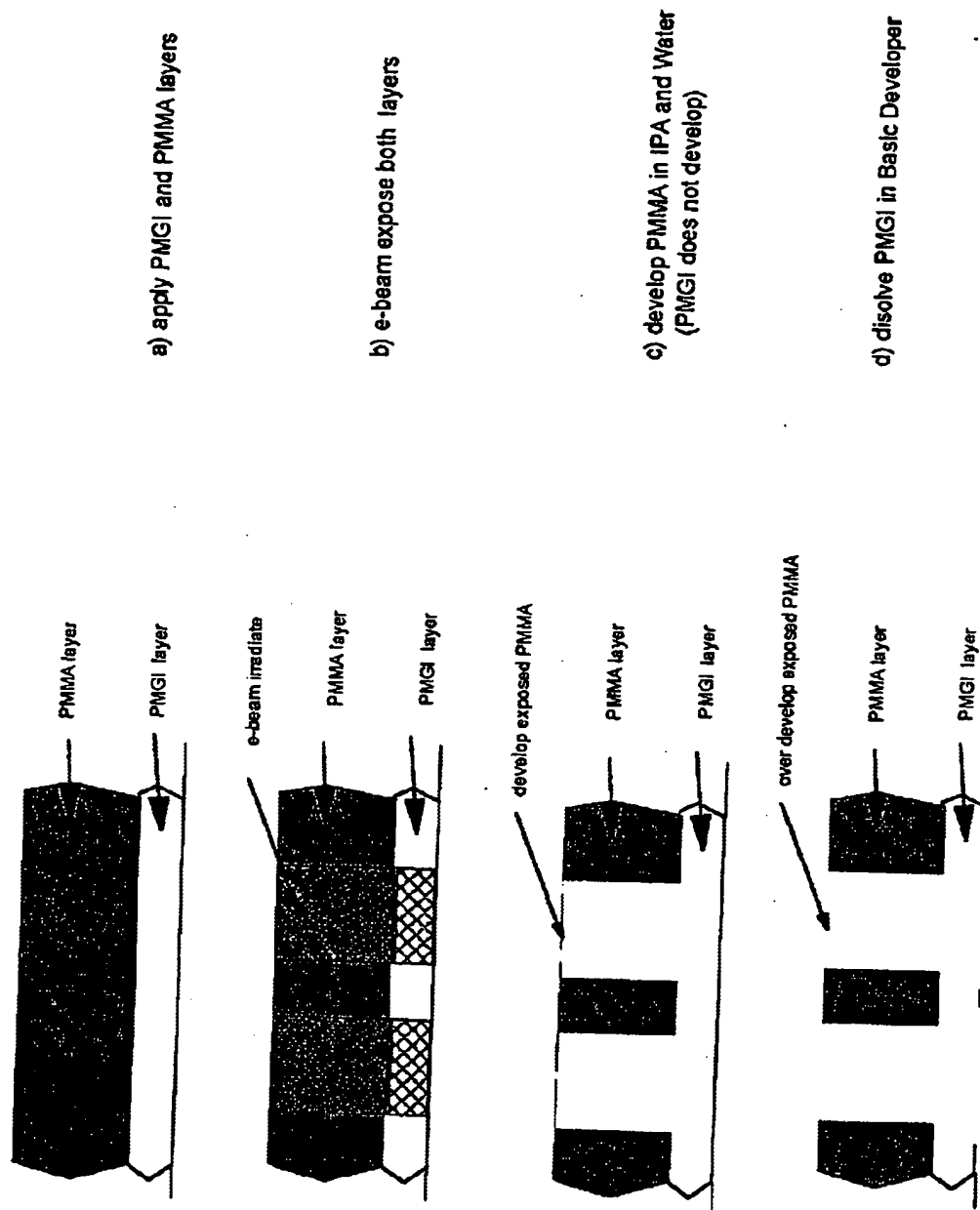


Figure 4. PMMA / PMGI Undercut Resist Structure

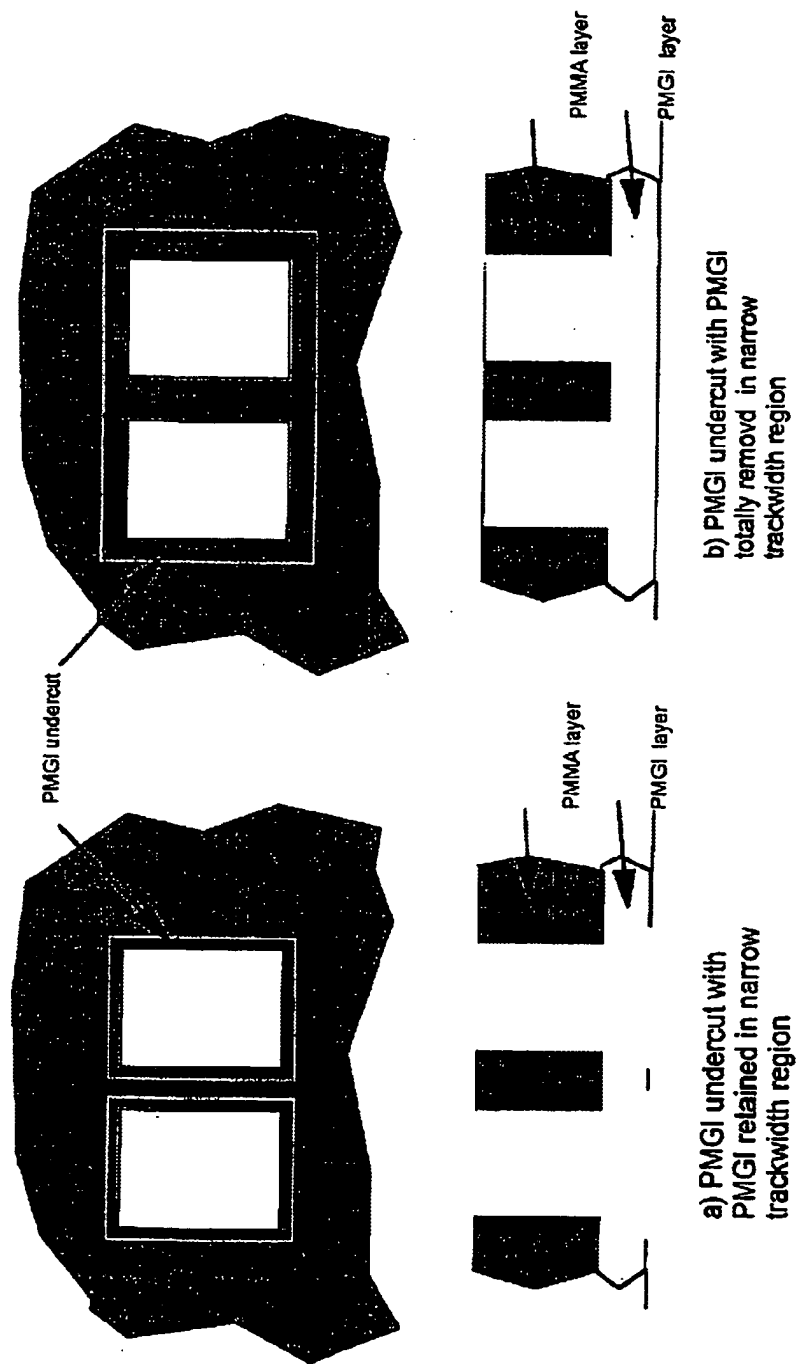


Figure 5. PMMA / PMGI Undercut Resist Structure with PMGI Removed in Critical Trackwidth Region

Figure 6. TEM Cross-section of Sensor Fabricated Using Suspended PMMA Bridge

